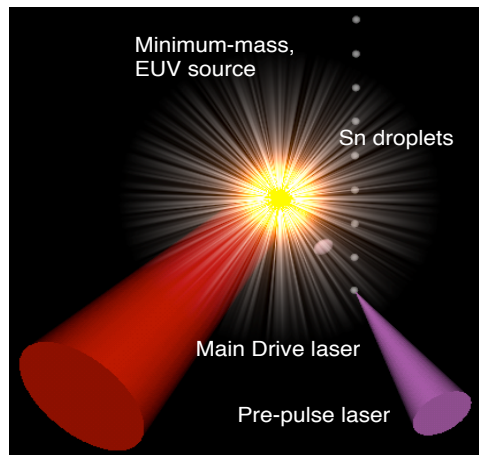


Measurement of CO₂ laser absorption by thin plasma as a 13.5 nm EUV light source

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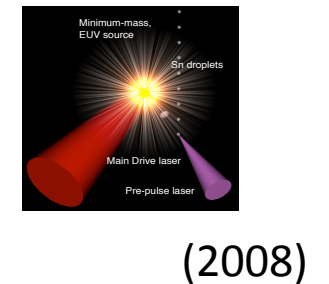
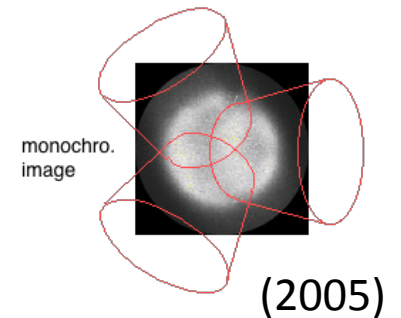
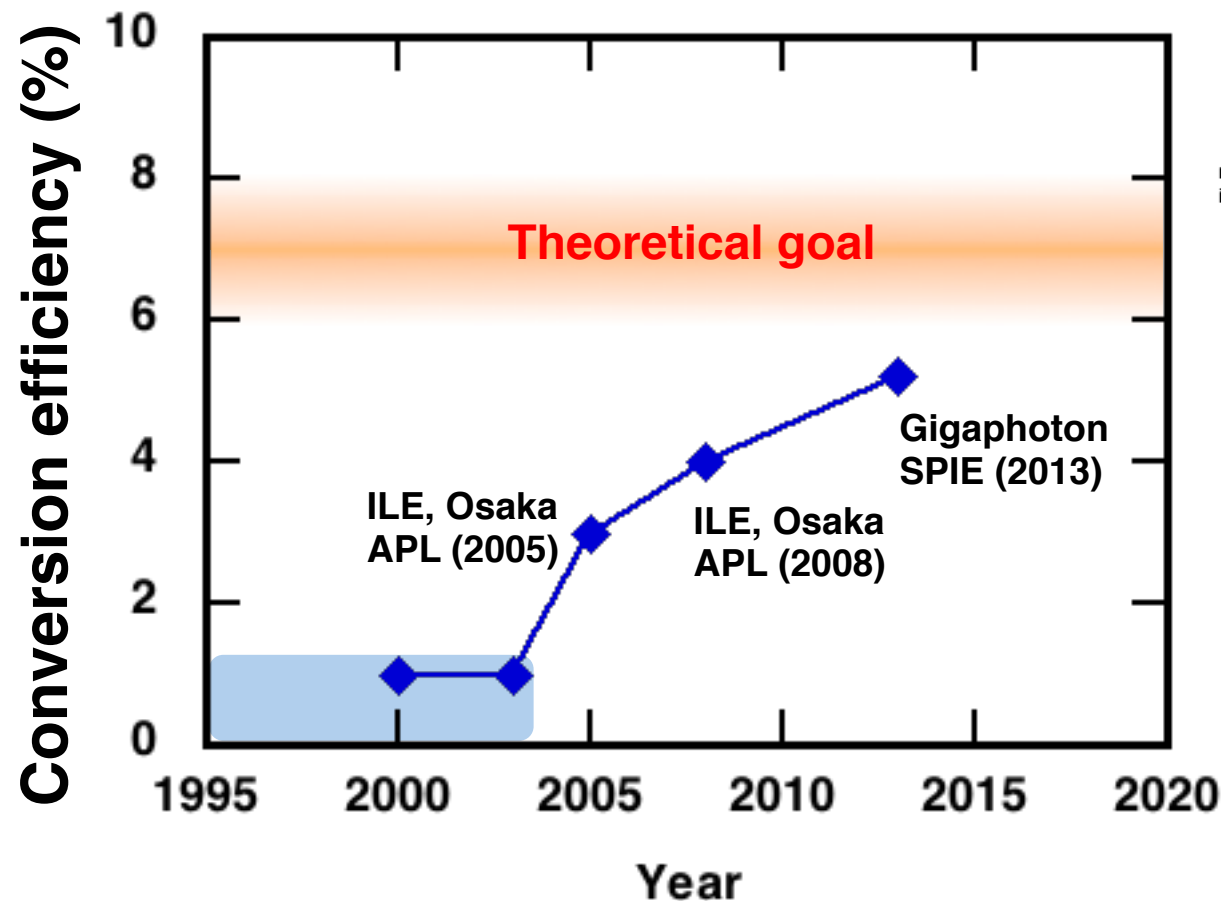
¹ Institute of Laser Engineering, Osaka University, Japan

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³ Gigaphoton Inc., Japan



Extensive studies have been made aiming at the theoretical goal of EUV conversion efficiency (CE)



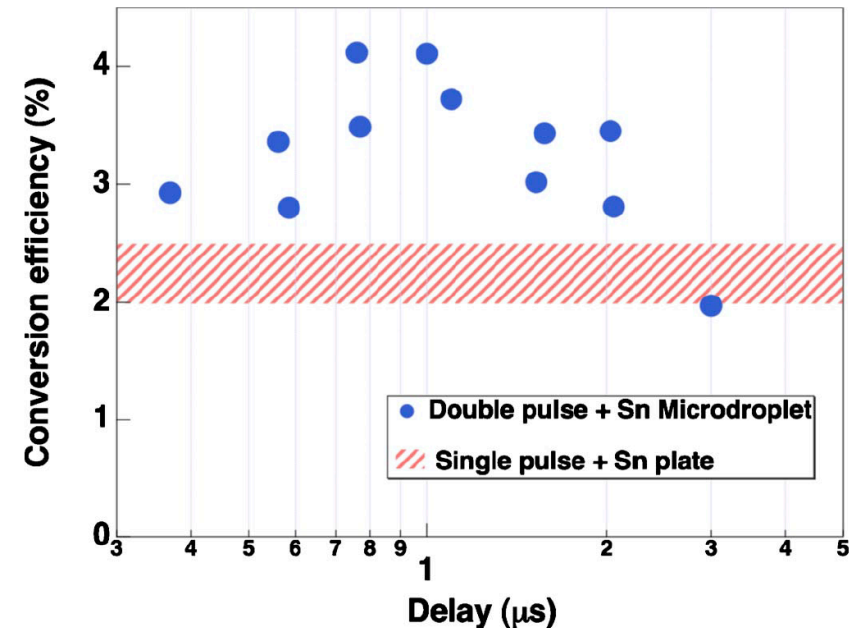
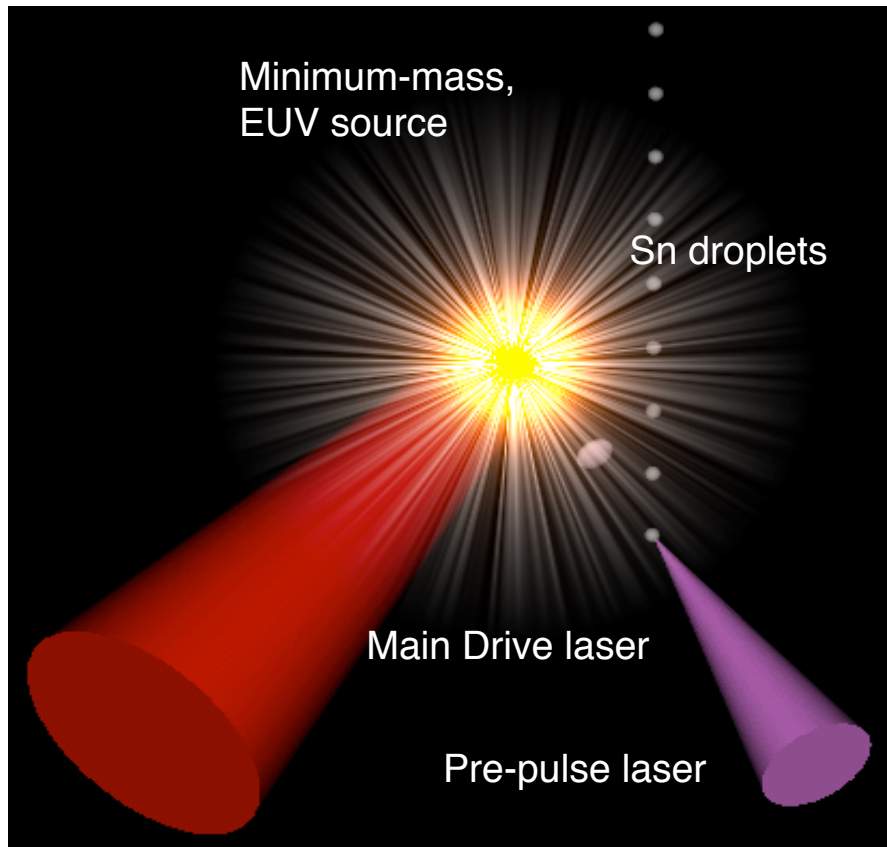
Use of ps-pulse
(2013)

Y. Shimda, et al., APL 86, 051501 (2005)

S. Fujioka, et al., APL 92, 241502 (2008)

H. Mizoguchi et al., Proc. SPIE 8679, 86790A (2013)

Two-color, double pulse scheme is widely adopted in EUV source for lithography

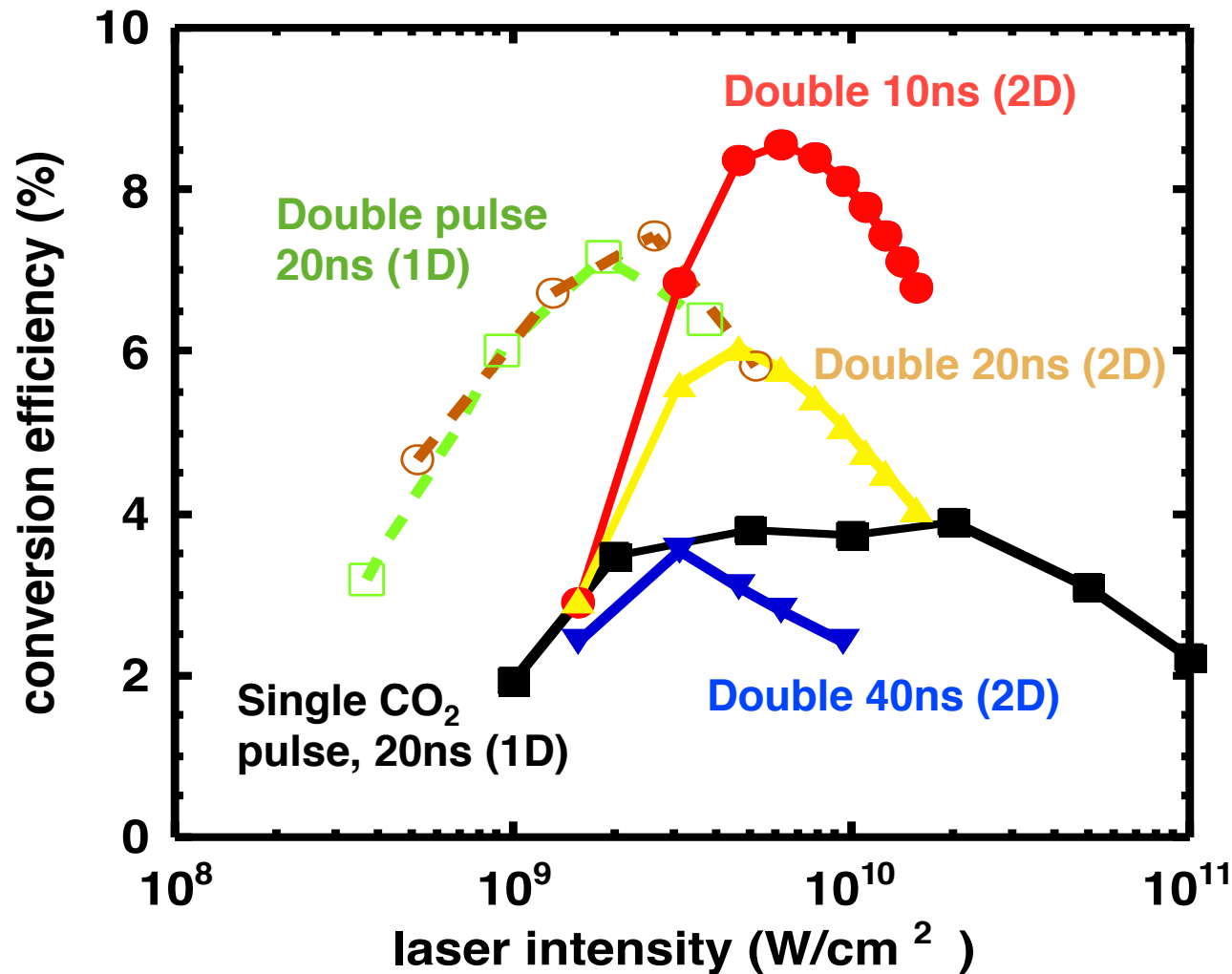


$$T_e, n_e, L_{\text{scale}}, \eta_{\text{abs}} ?$$

It is not clarified yet why CE is substantially increased, optimization plasma parameters or increase in laser absorption?

Predictions

Double pulse scheme affords 6-8% EUV CEs, twice larger than those given with a single pulse



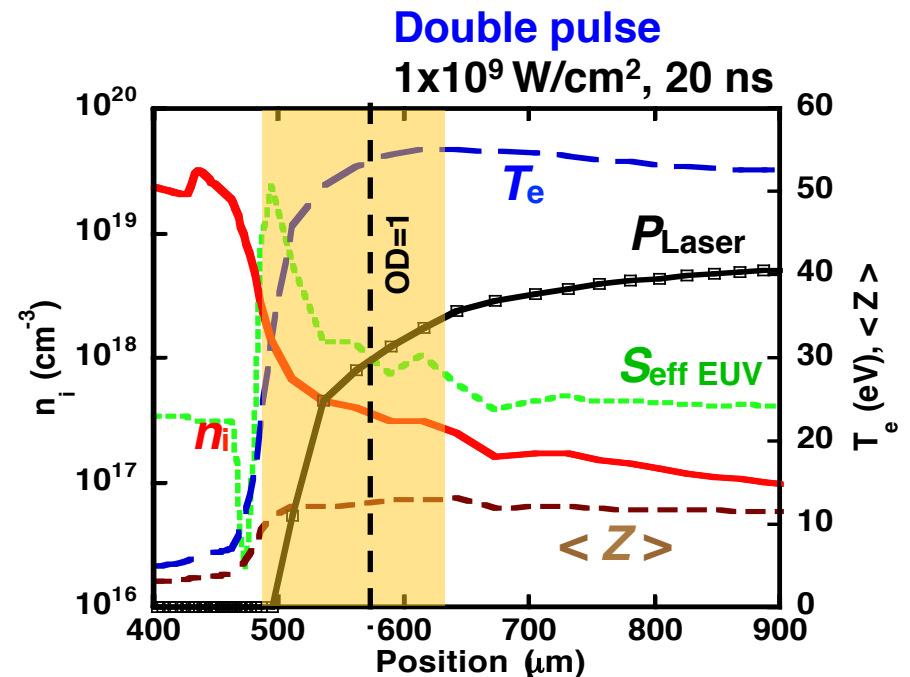
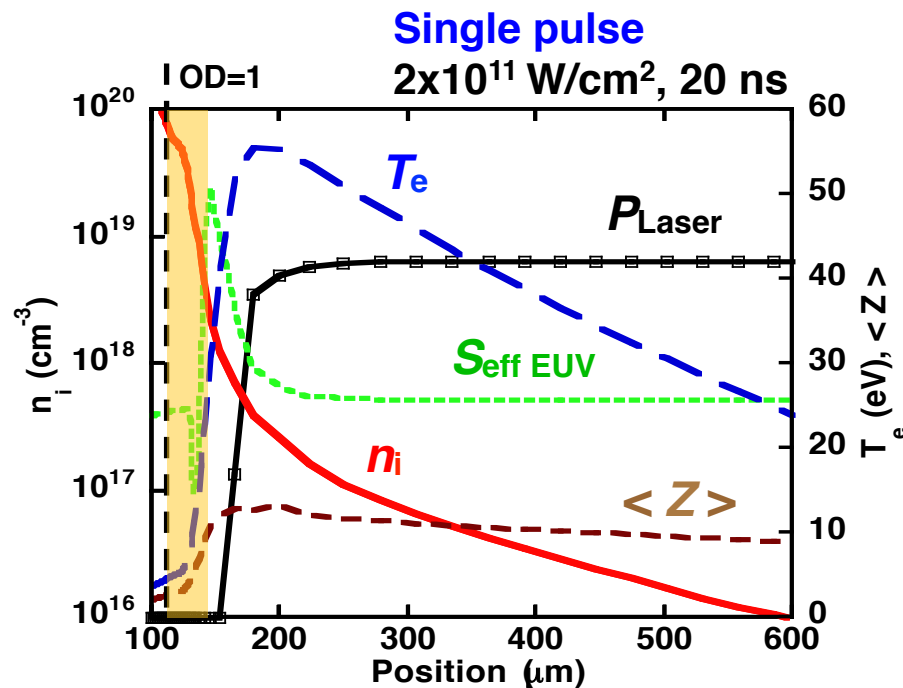
<Pre-pulse>
 $1 \times 10^8 \text{ W}/\text{cm}^2$
10ns ($0.53 \mu\text{m}$)
delay :180ns

In 2D simulation,
 $150 \mu\text{m}$ pre-formed
plasma is initially set.
Spot diameter is $800 \mu\text{m}$.

HULLAC Opacity
1500 groups in 0-1.5 keV

Predictions

Theoretical predictions infer that increase in EUV CE is resulted from increase in laser absorption



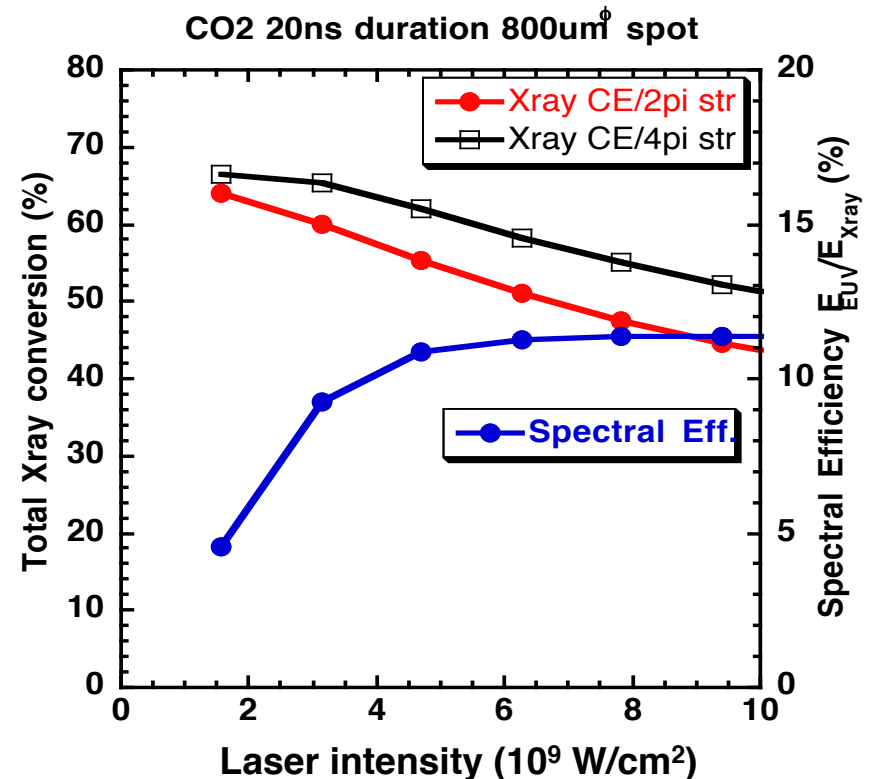
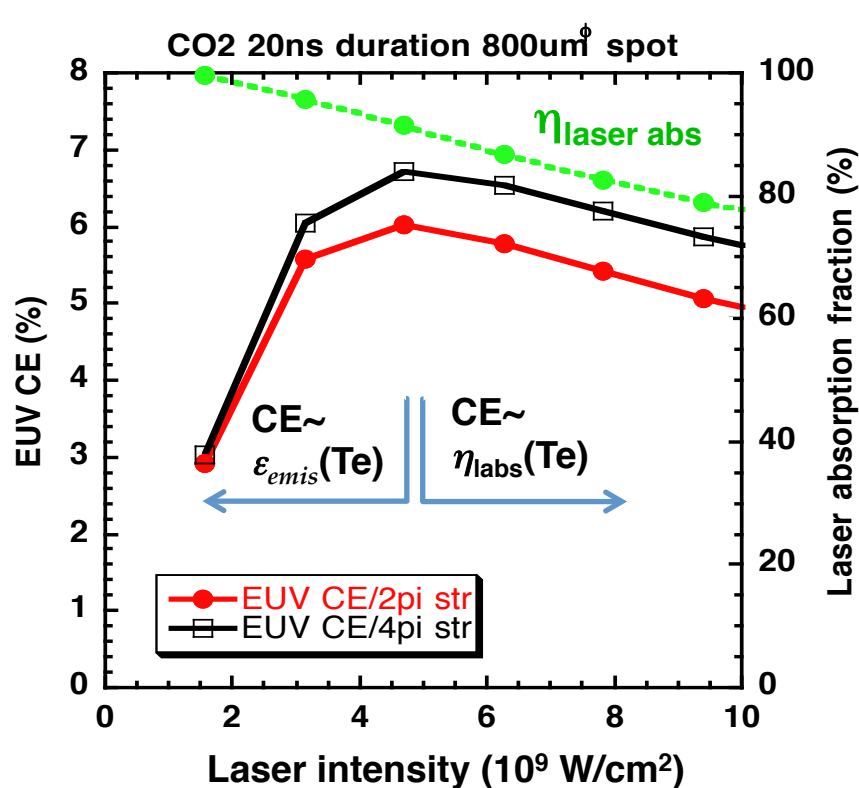
Single pulse Double pulse

Laser absorption	46%	91%	increase in laser abs.
Radiation CE	48%	69%	increase in rad. CE
$P_{\text{EUV}}/P_{\text{x-ray}}$	15%	11%	better spectral purity
EUV CE	3.3%	7.2%	increase in EUV CE

Predictions

With increase in laser intensity, two distinct regions appear for CE, dependent either on T_e or η_{labs}

$$\eta_{\text{laser abs.}} = 1 - \exp(-\tau L), \text{ where } \tau \propto n_i n_e T_e^{-7/2} Z^2$$

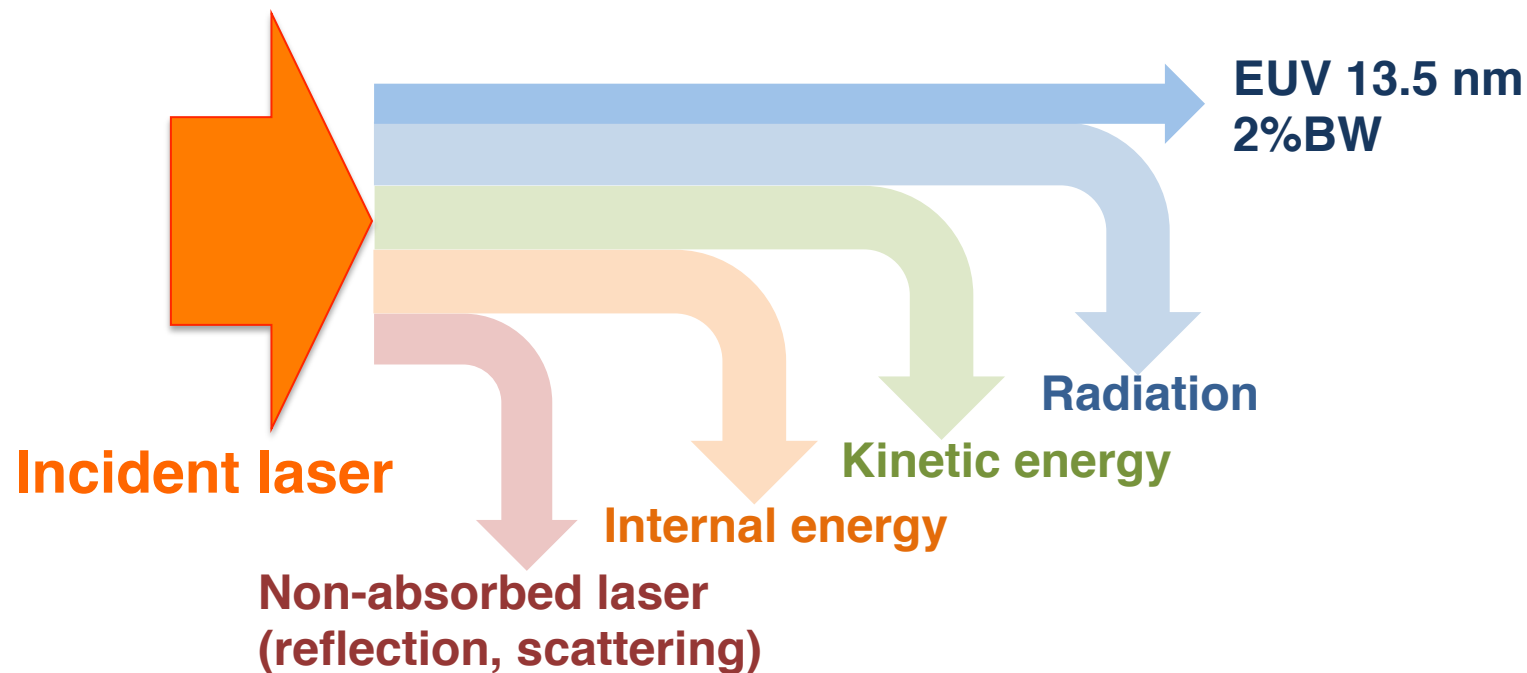


Objectives

1. Experimental verification of CE vs. η_{labs}
2. Optimization for higher η_{labs} hence better CE

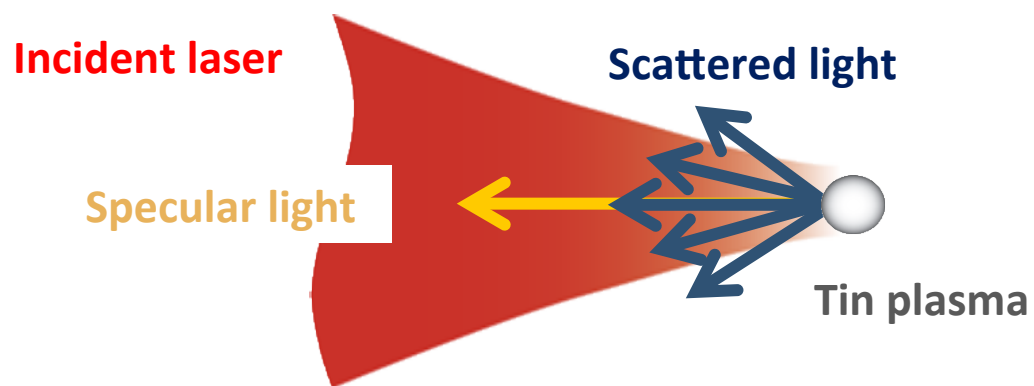
$$\eta_{\text{laser abs.}} = 1 - \exp(-\tau L), \text{ where } \tau \propto n_i n_e T_e^{-7/2} Z^2$$

Note: excessively long-scale plasma may result in reduction in CE due to “EUV self-absorption”

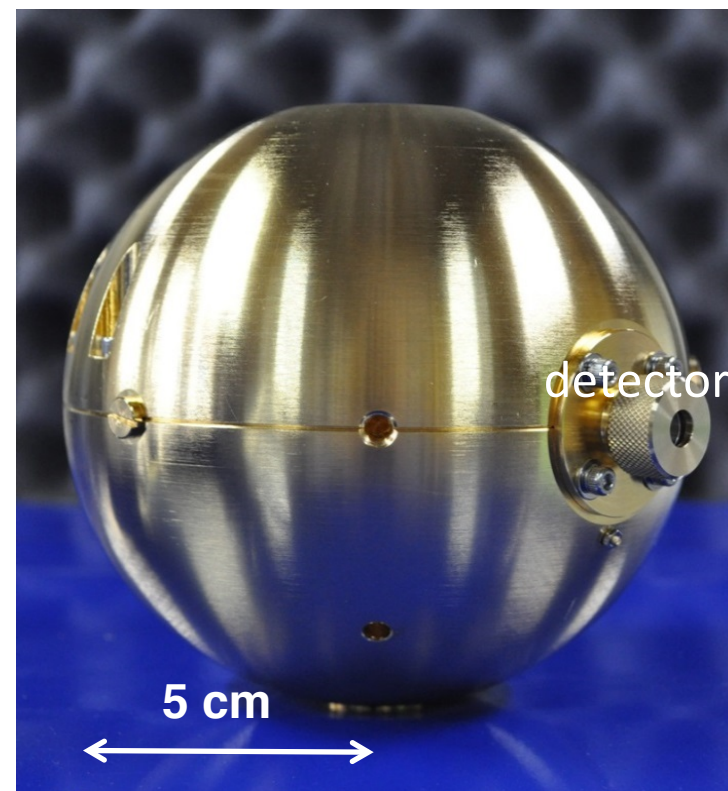


Experiment

We developed an integrating sphere for η_{labs} measurement of CO₂ laser by plasma

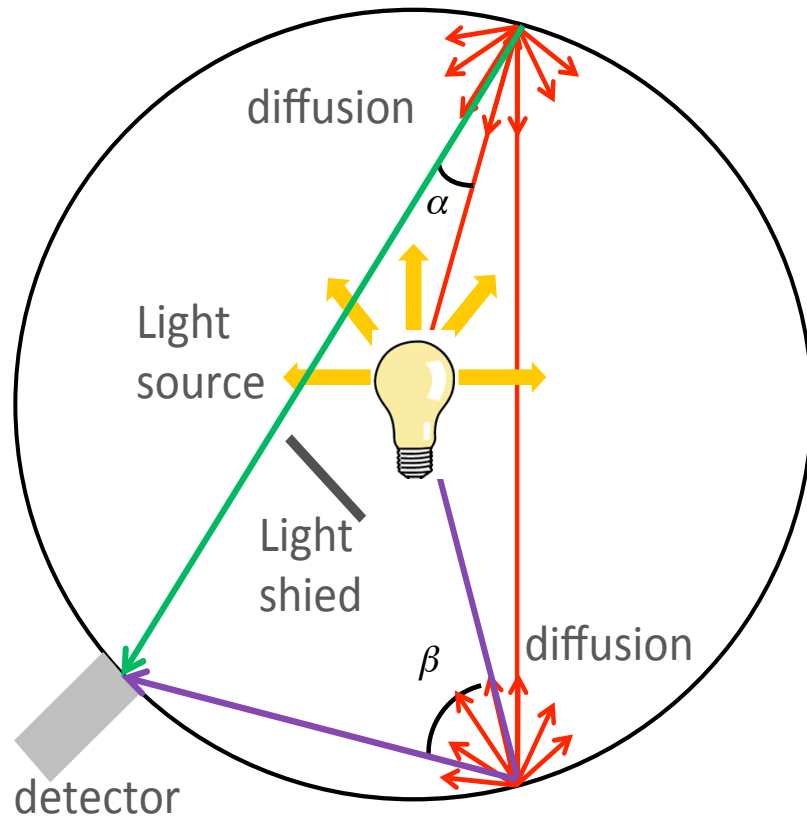


$$\eta_{\text{labs.}} = 1 - \frac{I_{\text{specular}} + I_{\text{scatter}}}{I_{\text{laser}}}$$



Experiment

Multi-reflection of scattered light homogenizes its distribution on the inner surface



Light intensity @detector

$$= \frac{\rho\Phi}{S} (1 + \rho + \rho^2 + \rho^3 + \rho^4 + \dots + \rho^{n-1})$$
$$= \frac{\Phi}{S} \frac{\rho}{1 - \rho}$$

Φ : light source power

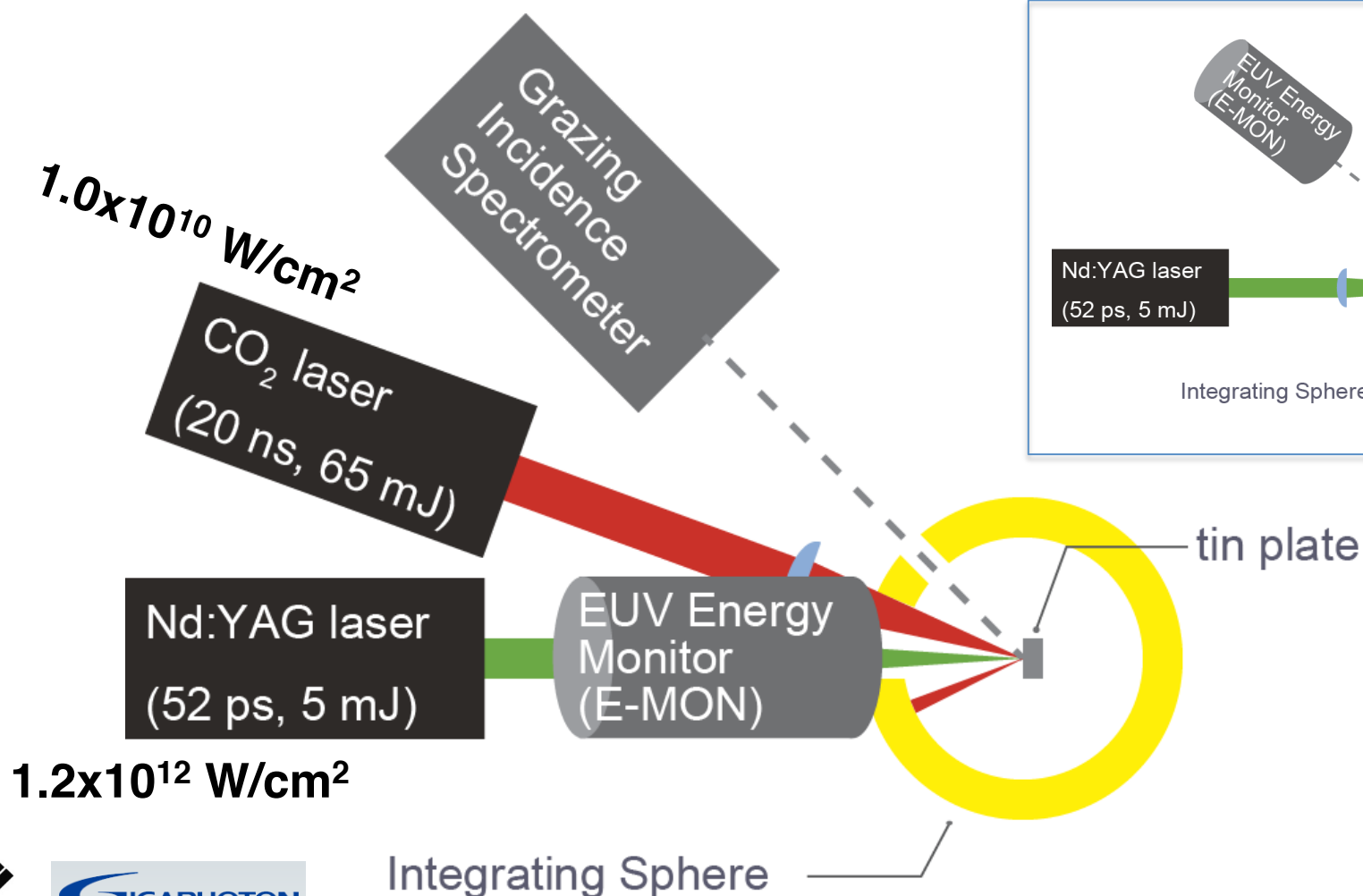
ρ : diffuse reflection factor

S : surface area of integrating sphere

EUV CEs and corresponding EUV spectra are measured simultaneously with η_{labs}

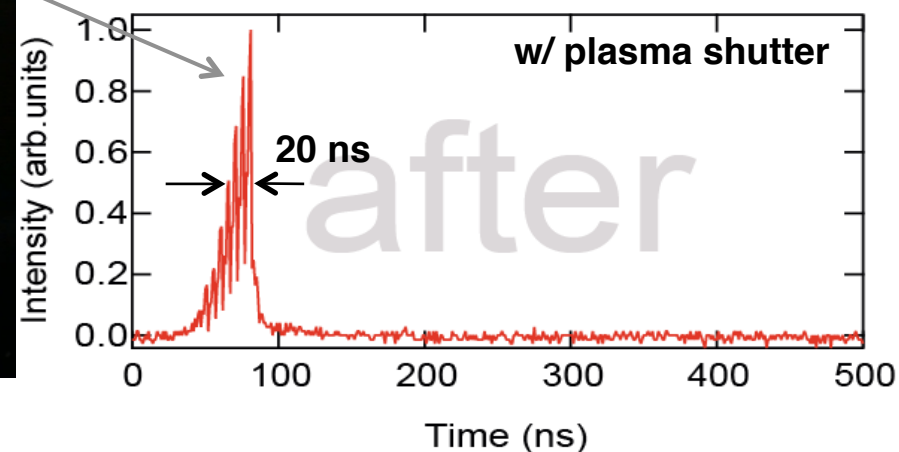
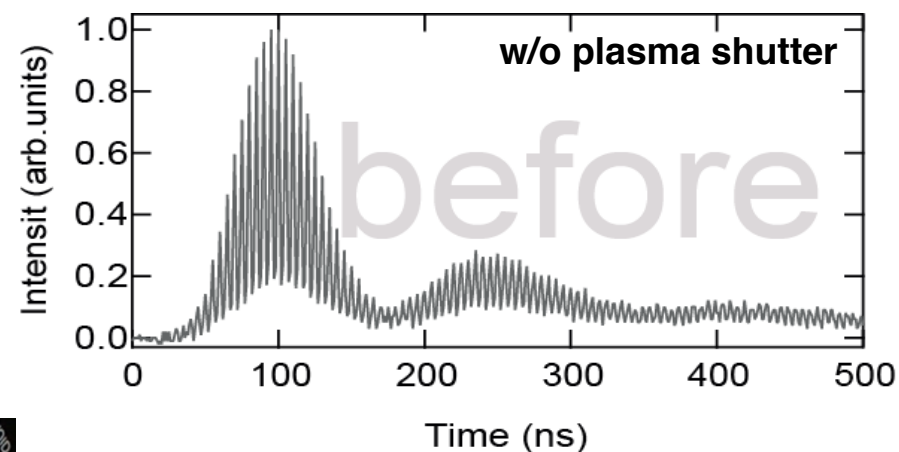
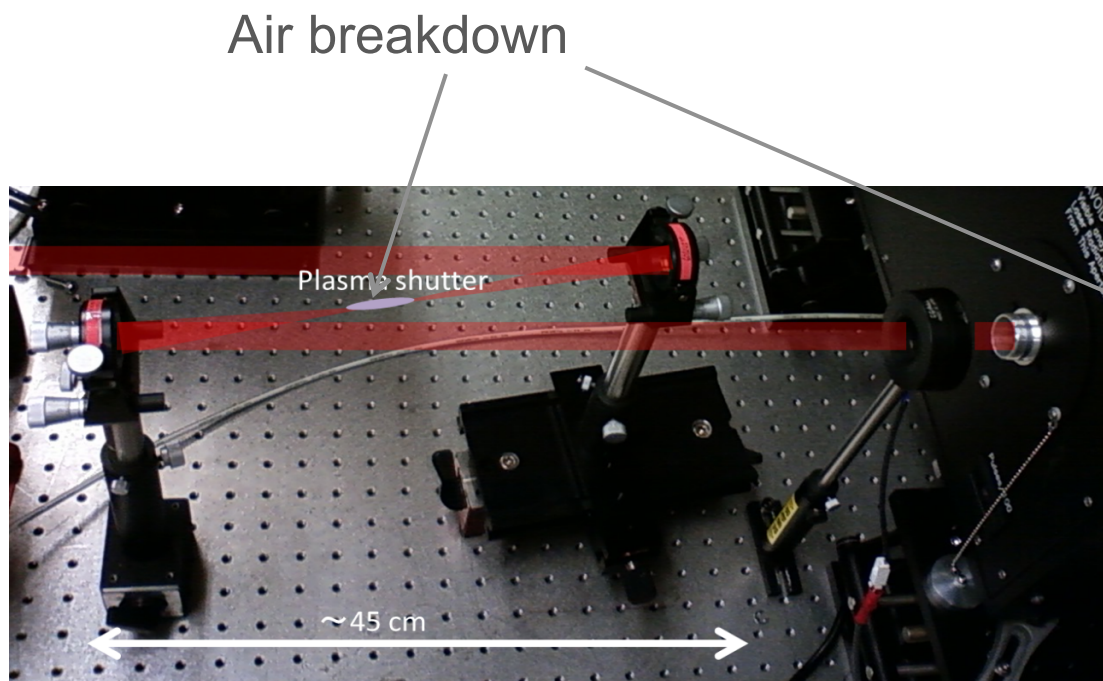
Top view

Side view

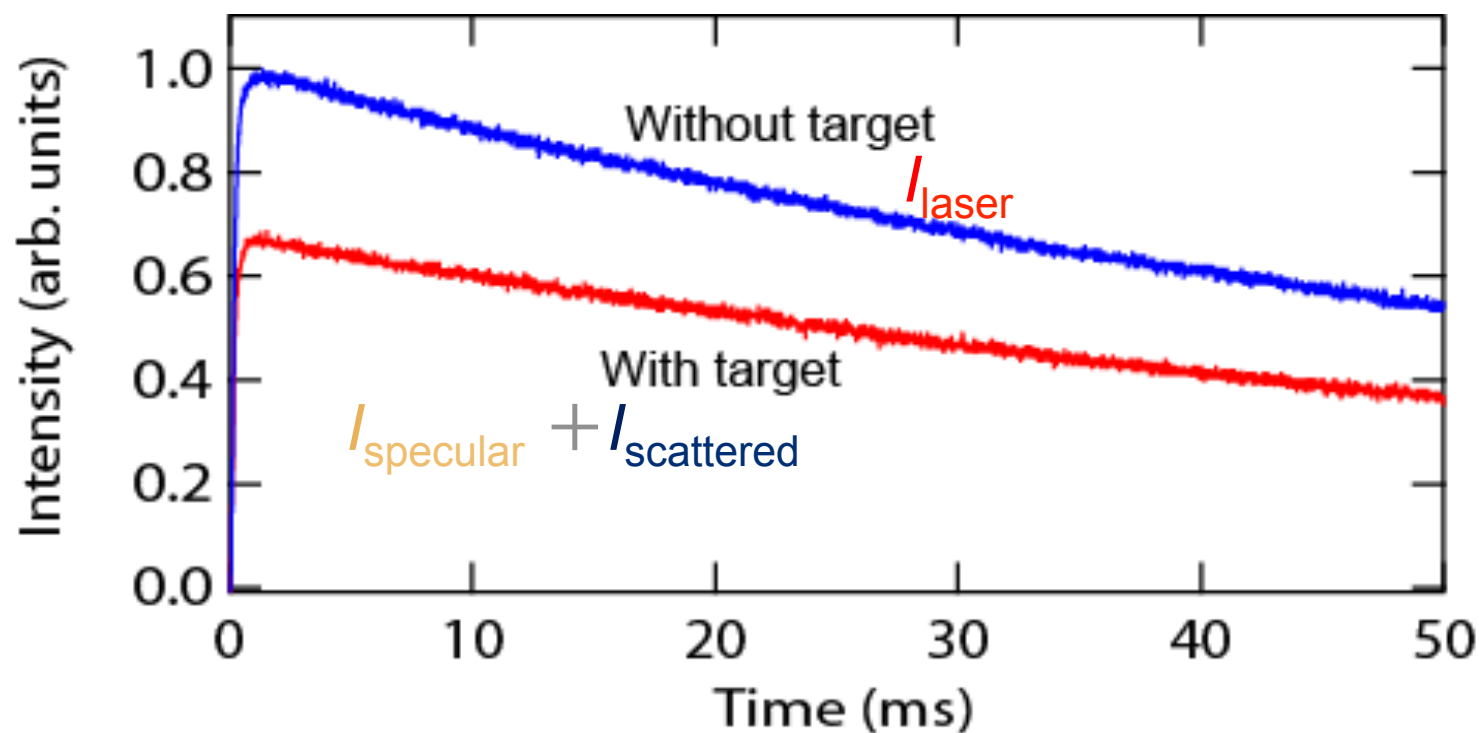


Experiment

Plasma Shutter shortens pulse width of CO₂ laser used in the experiment

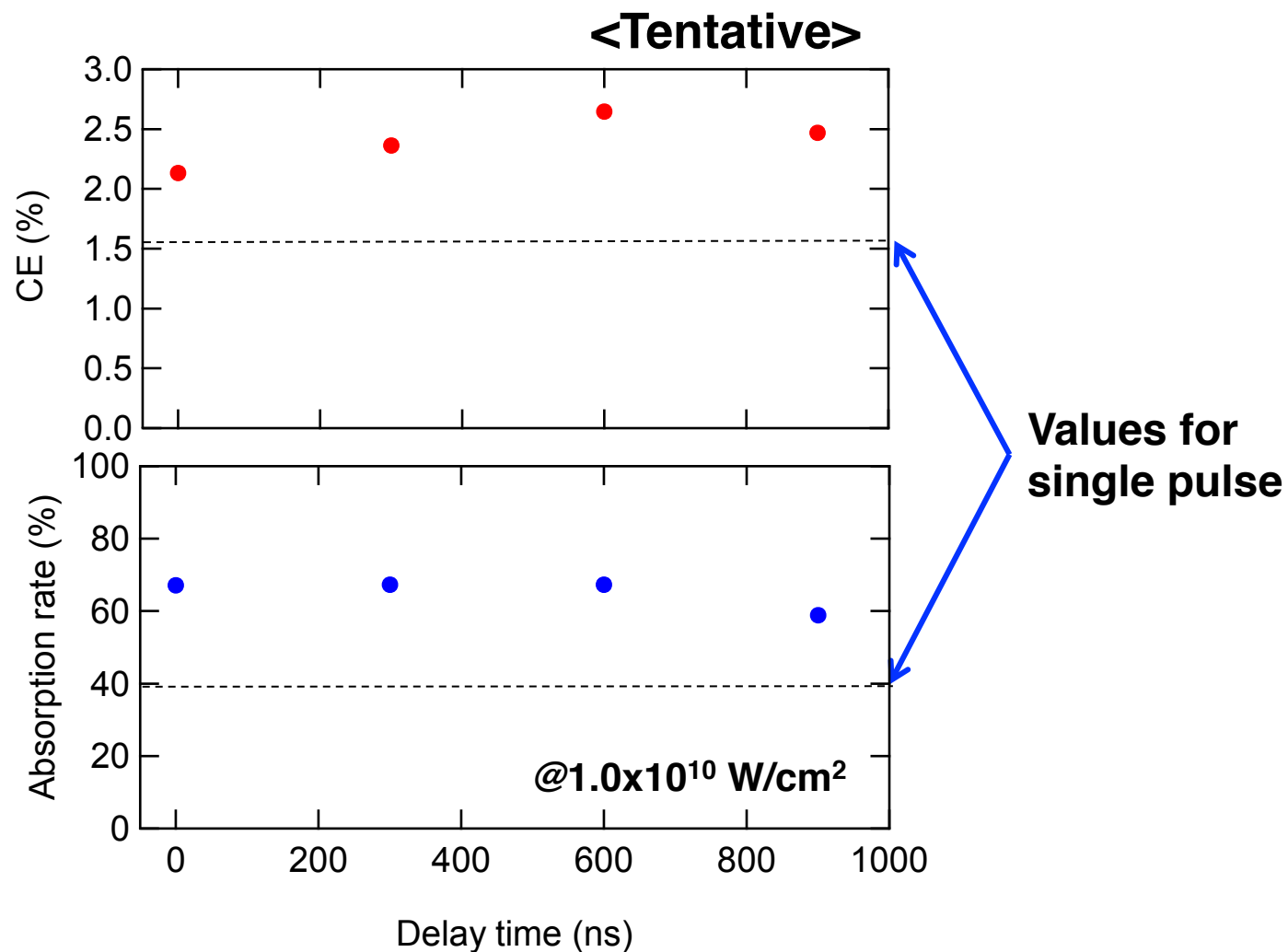


Reduced signal from the detector indicates absorption of CO₂ laser by plasma



$$\eta_{\text{laser abs.}} = 1 - \frac{I_{\text{specular}} + I_{\text{scatter}}}{I_{\text{laser}}}$$

Increase in CE and η_{labs} show clear correlation between them, validating theoretical predictions



Summary

- ☑ To improve EUV CE, increase of laser absorption rate is effective.**
- ☑ For validation, we have developed an integrating photo-sphere dedicated for CO₂ laser absorption measurement.**
- ☑ We measured EUV CE at 13.5 nm and the drive laser absorption rate for single- and double-pulse cases, and found tight correlation between them.**

Acknowledgements

This work was mainly supported by the collaboration with Gigaphoton Inc. under the frame of NEDO project of 2013-2104, and partly supported by the MEXT Project for Creation of Research Platforms and Sharing of Advanced Research Infrastructure 2014.